OS22 MEMS/NEMS OS22-02 Free standing diamond nanostructures formed by sacrificial layer etching for nanoelectromechanical lactuators Taro Ikeda and Yoshiaki Kanamori OS22-04 Design of a device for surface profile

measurement integrating 3x3 displacement sensors
Kotaro Nakahara, Tatsuki Noda, Naoya Shirozu, Yuuma

Tamaru and Hiroki Shimizu

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